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Solution

## EE 121B Quiz 2

You have 1 hour to finish the quiz. There are four problems.

Use  $T=300K$  unless specified otherwise. Make appropriate assumptions when necessary. Use algebraic expression only if you cannot calculate numerically based on the provided information.

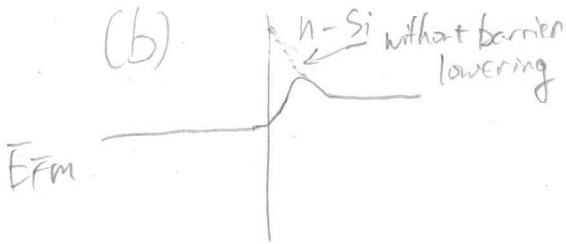
Constants and Equations			
$n_i = 1.5 \times 10^{10} \text{ cm}^{-3}$	$E_{g, Si} = 1.14 \text{ eV}$ $\chi_{Si} = 4.05 \text{ V}$	$\epsilon_{Si} = 1.04 \times 10^{-12} \text{ F/cm}$ $\epsilon_{ox} = 3.46 \times 10^{-13} \text{ F/cm}$	$q = 1.6 \times 10^{-19} \text{ C}$
$k_B = 8.617 \times 10^{-5} \text{ eV/K}$ $k_B T = 0.0259 \text{ eV at } T=300K$	$n_0 = n_i \exp\left[\frac{E_F - E_{Fi}}{kT}\right]$	$n_0 p_0 = n_i^2$	$\frac{\rho(x)}{\epsilon_s} = \frac{dE(x)}{dx} = \frac{-d^2\phi}{dx^2}$
$\tau_d = \frac{\epsilon}{\sigma}$	$\phi_{B0} = \phi_m - \chi$ $\phi_{ms} = \phi_m - \phi_s$	$W = x_n = \sqrt{\frac{2\epsilon_s}{qN_d} (V_{bi} + V_R)}$	$x_m = \sqrt{\frac{q}{16\pi\epsilon_s E}}$
$J = [A^* T^2 \exp\left(-\frac{q\phi_{Bn}}{kT}\right)] \left[\exp\left(\frac{qV_a}{kT}\right) - 1\right]$		$A^* = \frac{4\pi q m_n^* k^2}{h^3}$	$R_c = \left(\frac{\partial J(V=0)}{\partial V}\right)^{-1}$
$E_g - q\phi_0 - q\phi_{Bn} = \frac{1}{qD_{it}} \sqrt{2q\epsilon_s N_d (\phi_{Bn} - \phi_n)} - \frac{\epsilon_i}{qD_{it}\delta} [\phi_m - (\chi + \phi_{Bn})]$			
$C' = \epsilon/t$ $Q' = C'V$	$\phi_{fp} = \frac{kT}{q} \ln\left(\frac{N_a}{n_i}\right)$	$x_d = \sqrt{\frac{2\epsilon_x \phi_s}{qN_a}}$	$x_{dmax} = \sqrt{\frac{4\epsilon_x \phi_{fp}}{qN_a}}$
$n_{st} = n_i \exp(q\phi_{fp}/kT)$ $n_s = n_{st} \exp(q\Delta\phi_s/kT)$	$V_{FB} = \phi_{ms} - \frac{Q'_{ss}}{C_{ox}}$	$ Q'_{SD}(max)  = qN_a x_{dmax} = qN_d x_{dmax}$	
$V_{TN} = V_{FB} + \frac{ Q_{SD}(max) }{C_{ox}} + 2\phi_{fp}$		$V_{TP} = V_{FB} - \frac{ Q_{SD}(max) }{C_{ox}} - 2\phi_{fn}$	
$C'_{FB} = \frac{\epsilon_{ox}}{t_{ox} + \left(\frac{\epsilon_{ox}}{\epsilon_s}\right) \sqrt{\frac{kT\epsilon_s}{q^2 N_a}}}$		$I_D = \frac{W\mu_n C_{ox}}{2L} [2(V_{GS} - V_T)V_{DS} - V_{DS}^2]$	
$V_G = V_{ox} + V_{sc}$		$I_D = \frac{W\mu_p C_{ox}}{2L} [2(V_{SG} + V_T)V_{SD} - V_{SD}^2]$	
$\Delta V_T = \frac{\sqrt{2q\epsilon_s N_a}}{C_{ox}} \left[ \sqrt{2\phi_{fp} + V_{SB}} - \sqrt{2\phi_{fp}} \right]$		$f_T = \frac{\mu_n (V_{GS} - V_T)}{2\pi L^2}$	
$C_{it} = qD_{it}$		$I_D(sub) \propto \left[\exp\left(\frac{qV_{GS}}{kT}\right)\right] \left[1 - \exp\left(-\frac{qV_{DS}}{kT}\right)\right]$	
$I'_D = \left(\frac{L}{L - \Delta L}\right) I_D(sat) \approx \frac{W\mu_n C_{ox}}{2L} [(V_{GS} - V_T)^2 (1 + \lambda V_{DS})]$			

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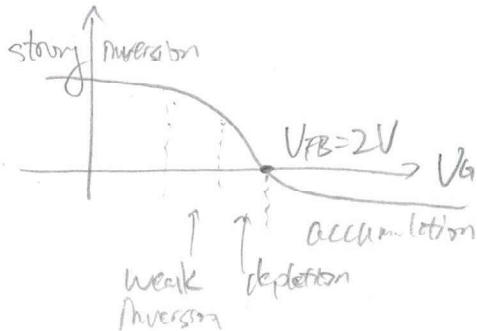
1. Short answer questions, you need to answer all of them (8% \* 4 = 32%)
  - (a) What are the two types of Ohmic contact in the metal-Si system? What are the similarities and the fundamental differences between them? (2) (3)
  - (b) Draw a band diagram to show the Schottky barrier lowering (n type Si). Briefly explain the physics behind it. (4) (4)
  - (c) Let the surface band bending  $\psi_{SBB}$  be positive when the band bends up from the bulk to the oxide-Si interface. Sketch  $\psi_{SBB}$  with respect to  $V_G$  of a MOSCAP with n-type Si and  $V_{FB} = 2V$ . Label the accumulation, depletion, (weak) inversion and strong inversion. (4)
  - (d) What does pinch-off mean for a MOSFET? What's the relationship between  $V_{GS}$  and  $V_{DS}$  at pinch-off for a p channel MOSFET? (5) (2)

(a) ideal non-rectifying barrier & tunneling barrier (2)  
 drift current tunneling current  
 They are both non-rectifying, majority carrier dominated.



The barrier is lowered at the interface due to the Coulomb force from the metal, which can be described by the image charge theory

(c)  $V_G \uparrow$ ,  $\psi_{SBB} \downarrow$  due to depletion



(d) Pinch-off means that part of the MOSFET channel is depleted while part of it has the strong inversion layer channel. It creates "saturation" region as a result

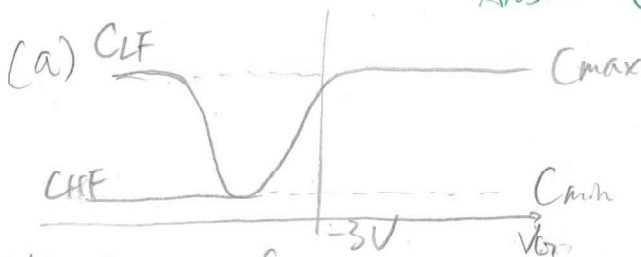
For p channel MOSFET, at pinch-off  $V_{SD} > V_{SG} + V_T$

or  $-V_{DS} > -V_{GS} + V_T$

2. A MOSCAP has n-type Si with ideal oxide (no associated charges) and  $\phi_{ms} = -3V$ . (28%)
- (a) Sketch its low frequency and high frequency C-V characteristics. (4%)
  - (b) What are the extreme values for the capacitance in your plots for (a)? Why? (4%)
  - (c) What are the approximate maximum and minimum of the frequency that is applicable for the high frequency C-V curve you sketched? (4%)
  - (d) Sketch its low frequency and high frequency C-V characteristics if there are some interface trapped charges  $D_{it}$ . What is changed by the interface trapped charge? (6%)
  - (e) How can you measure  $D_{it}$  in the MOSCAP? (2%)
  - (f) Derive the equation you need for the measurement in (e). (8%)

parallel C<sub>it</sub> model (4)

Answer (9)



(b)  $C_{max} \approx C_{ox}$

$$C_{min} \approx \left( \frac{1}{C_{ox}} + \frac{1}{C_{sc, min}} \right)^{-1}$$

$$= \left( \frac{t_{ox}}{\epsilon_{ox}} + \frac{x_{dmax}}{\epsilon_s} \right)^{-1}$$

At strong inversion/accumulation (LF)  
 $dQ$  is at the surface of Si

$\Rightarrow C_{max} \rightarrow C_{ox}$

At inversion  $dQ$  is also at the depletion region edge

$C \approx C_{ox} \parallel C_{sc}$

At strong inversion (HF)

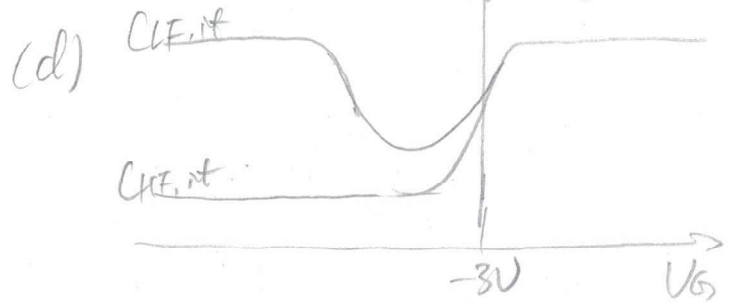
$C \rightarrow C_{ox} \parallel C_{sc, min}$

$x_{dmax}$   
 $dQ$  at inversion layer

(c) For CHF

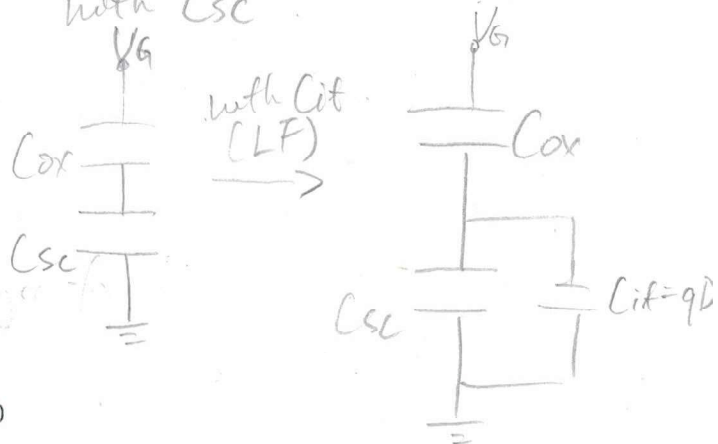
$f >$  (minority carrier lifetime at Si)  $\sim 10^6$  Hz

$f <$  (dielectric relaxation time at Si)  $\sim 10^{12}$  Hz



$D_{it}$  cannot respond to HF  $\rightarrow$  no charge for CHF

At LF,  $D_{it}$  works as capacitor in parallel with  $C_{sc}$



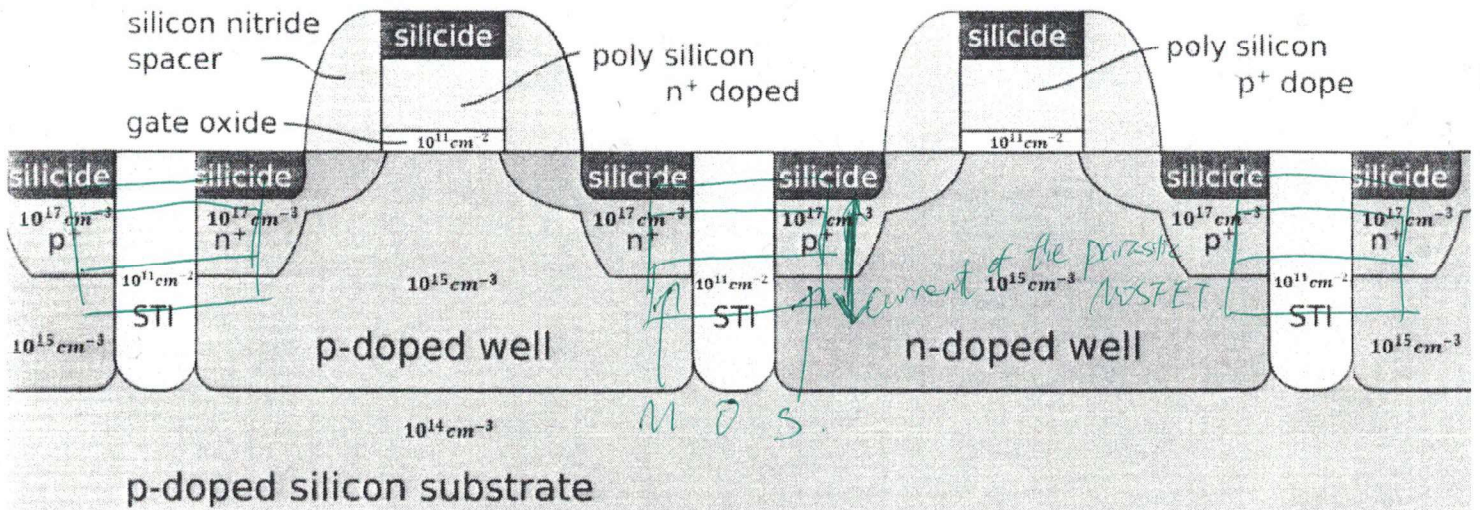
(e) Use CHF, CLF of the capacitor.

$$(f) \begin{cases} CLF = C_{ox} // (C_{sc} + qDie) \\ CHF = C_{ox} // (L_{sc}) \end{cases} \Rightarrow Die = \frac{1}{q} \left( \frac{C_{ox} CLF}{C_{ox} - CLF} - \frac{C_{ox} CHF}{C_{ox} - CHF} \right)$$

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3. The CMOS technology makes the MOSFET in "pairs" in a periodic fashion as shown in the figure. Here you can consider the spacer as insulator, silicide as a conductive material whose work function difference with silicon is very small. STI (shallow trench insulator) is  $\text{SiO}_2$ . The numbers indicate the doping concentration in the Si ( $10^{17} \text{cm}^{-3}$  for  $n^+$  or  $p^+$ ,  $10^{15} \text{cm}^{-3}$  for p or n doped well and  $10^{14} \text{cm}^{-3}$  for the Si substrate) and the equivalent fixed charge density in the oxide ( $10^{11} \text{cm}^{-2}$ ). (30%)

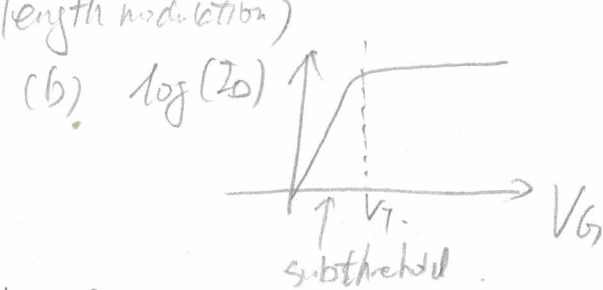
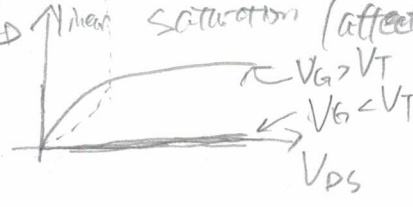


For (a), (b), (c), you don't necessarily need the figure.

- (a) Sketch the  $I_D(V_{DS})$  of the n channel MOSFET for  $V_{GS} > V_T$  and  $V_{GS} < V_T$ . Which part of the curve is affected by the channel length modulation? Label the linear (triode) region and saturation region. (4%)
- (b) Sketch  $I_D(V_{GS})$  of the n channel MOSFET and label the subthreshold region. (3%)
- (c) Suppose the only difference between the n channel MOSFET and the p channel MOSFET is the doping type, which transistor will in general be "better"? Why? (3%)
- (d) The thickness of the gate oxide is 20nm, what is the threshold voltage of the n channel MOSFET? (10%)
- (e) In this structure, there are some "parasitic transistors". Circle them in the figure. (2%)
- (f) How do these parasitic transistors affect the performance of the CMOS transistors? How can you suppress this effect in the design of such structure? (8%)

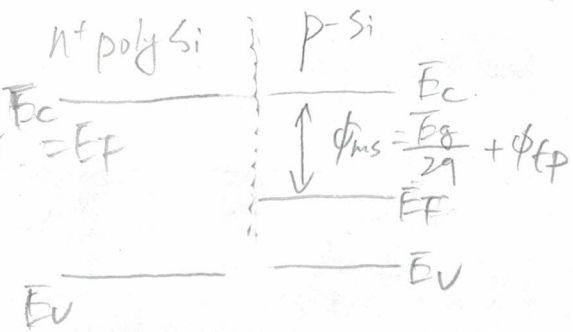
Equation ①  $\phi_{fp}$  ①  $\phi_{ms}$  ②  $V_{FB}(Q_{ss})$  ②  $Q_{ss}$  ② Answer ②

3. (a)  $\mu_{\text{linear}}$  saturation (affected by channel length modulation)



(c) NMOSFET,  $\mu_n > \mu_p \Rightarrow$  device has faster switching

(d)  $V_{TN} = V_{FB} + 2\phi_{FP} + \frac{|Q_{SDmax}|}{C_{ox}}$ ,  $\phi_{FP} = \frac{E_g}{2q} \ln\left(\frac{N_A}{n_i}\right) = 0.288V$ ,  $C_{ox} = \frac{\epsilon_{ox}}{t_{ox}} = 1.73 \times 10^{-8} \text{ F/cm}^2$



$$V_{FB} = \phi_{ms} - \frac{Q_{SS}}{C_{ox}} = \frac{E_g}{2q} + \phi_{FP} - \frac{q \cdot 10^{18} \text{ cm}^{-3}}{C_{ox}}$$

$$= 0.77V$$

$$|Q_{SDmax}| = q N_A x_{dmax} = \sqrt{4\epsilon_s \phi_{FP} N_A q}$$

$$= 1.38 \times 10^{-8} \text{ C}$$

$$\Rightarrow V_{TN} = V_{FB} + 2\phi_{FP} + \frac{|Q_{SDmax}|}{C_{ox}}$$

$$= 0.77V + 0.575V + 0.08V \approx 1.42V$$

(e) Boxed in the figure (one of the possible answers)

(f) if  $n^+$  or  $p^+$  is at a large bias it might create the inversion layer at the other side of STI, current can thus flow in the vertical direction in the neighbor MOSFET.

To suppress this, you need to make high  $V_t$  for this parasitic MOSFET.

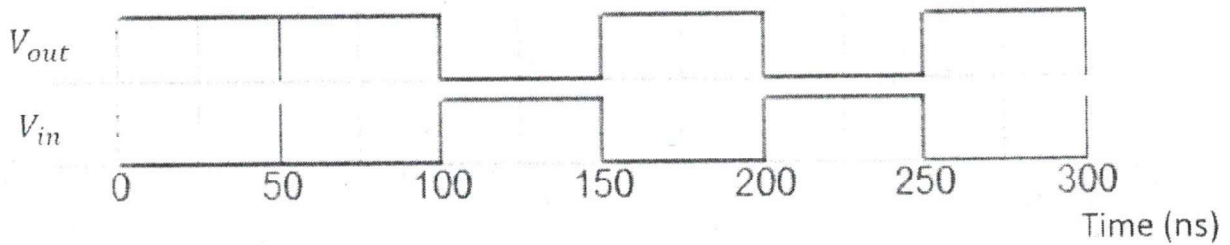
$$V_{TN} = V_{FB} + 2\phi_{FP} + \frac{|Q_{SDmax}|}{C_{ox}}$$

$\Rightarrow$  make smaller  $C_{ox} \Rightarrow$   $\left\{ \begin{array}{l} \text{thicker STI} \\ \text{low } k \text{ in STI} \end{array} \right.$  (horizontal direction)

Change doping level is also possible, but it will affect the original MOSFET.

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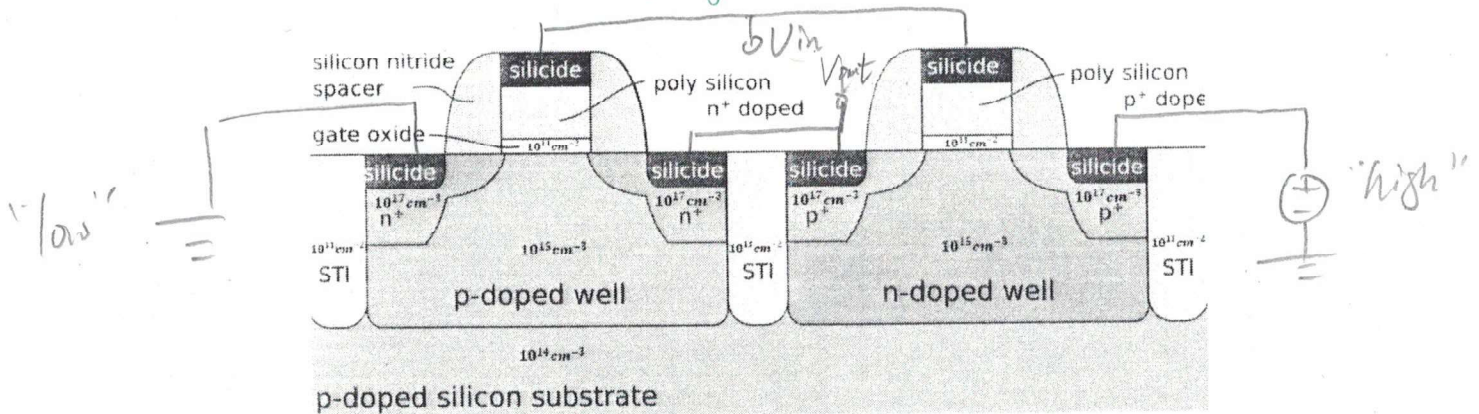
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4. An inverter is a basic digital circuit building block. The input/output characteristics of an ideal inverter is shown in the figure: whenever  $V_{in}$  is "low",  $V_{out}$  is "high" and vice versa. Consider a pair of the n and p channel MOSFETs from Problem 3. ~~(12%)~~ 10%

(a) How would you wire them up with necessary voltage and current supplier to implement an inverter? Show it in the provided structure below. (6%) 4%

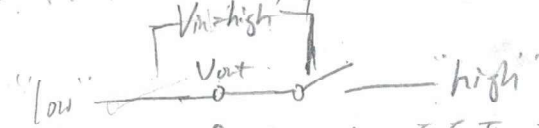
*Inverter wire at MOSFET*  
*Voltage Supplies*



(b) Explain how it works. You may use circuit symbols for the transistors to explain the operation. (6%)

When  $V_{in}$  is "high", nMOSFET is on, pMOSFET is off.

$\Rightarrow V_{out} = \text{"low"}$



When  $V_{in}$  is "low", nMOSFET is off, pMOSFET is on.

$\Rightarrow V_{out} = \text{"high"}$

